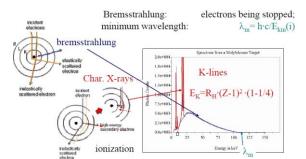
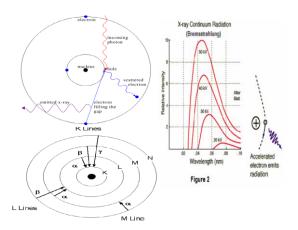
Physics of X-ray Sources

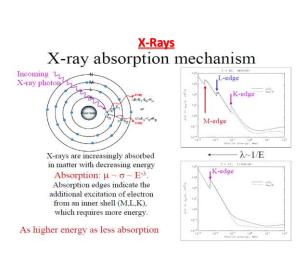
Char. X-Rays: $E_x = h \cdot v = h \cdot c/\lambda = \Delta E_{kin} = E_{kin}(i) - E_{kin}(f)$





X-ray beam The X-ray energy distribution is characterized by Bremstrahlung and characteristic lines depending on anode material and electron energy. The use of filters originates a quasi-monochromatic X-rays be Characteristic X-rays be The X-ray energy distribution is characterized by Bremstrahlung and characteristic lines depending on anode material and electron energy. The use of filters originates a quasi-monochromatic X-rays be The X-ray energy distribution is characterized by Bremstrahlung and characteristic lines depending on anode material and electron energy. The use of filters originates a quasi-monochromatic X-rays be The X-ray energy distribution is characterized by Bremstrahlung and characteristic lines depending on anode material and electron energy. The use of filters originates a quasi-monochromatic X-rays be The X-ray energy distribution is characterized by Bremstrahlung and characteristic lines depending on anode material and electron energy. The use of filters originates a quasi-monochromatic X-rays be The X-ray energy distribution is characterized by Bremstrahlung and characteristic lines depending on anode material and electron energy. The use of filters originates a quasi-monochromatic X-rays be The X-ray energy distribution is characterized by Bremstrahlung and characteristic lines depending on anode material and electron energy. The use of filters originates a quasi-monochromatic X-rays be a second or characteristic lines depending and characteristic lines depending

Low energy x-rays are absorbed in filter material



Introduction

Motivation

X-ray diffraction is used to obtain structural information about crystalline solids.

Useful in biochemistry to solve the 3D structures of complex bio-molecules.

Bridge between physics, chemistry, and biology.

X-ray diffraction is important for
Solid-state physics
Biophysics
Medical physics
Chemistry and Biochemistry

What is X-ray

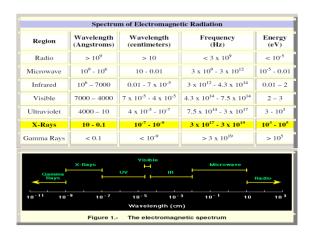
Beams of electromagnetic radiation

* smaller wavelength than visible light,

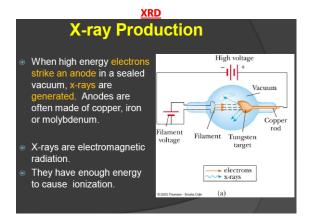
*higher energy

*more penetrative

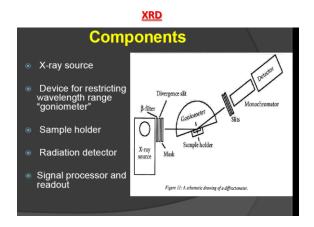
| hicrosoling energy | hicro

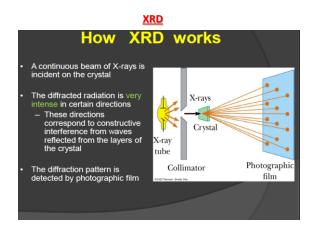


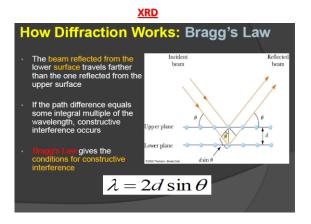


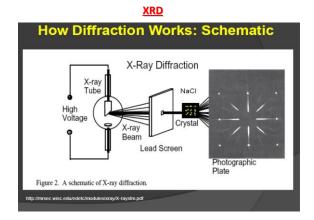


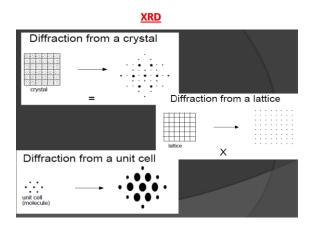


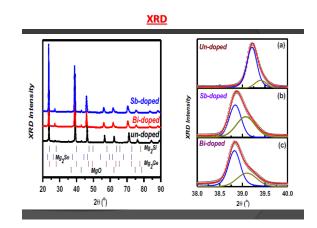


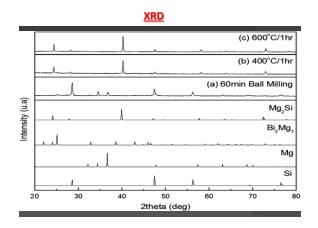












Single Crystal X-ray Diffraction Used to determine crystal structure orientation degree of crystalline perfection/imperfections (twinning, mozaicity, etc.) Sample is illuminated with monochromatic radiation Easier to index and solve the crystal structure because it diffraction peak is uniquely resolved

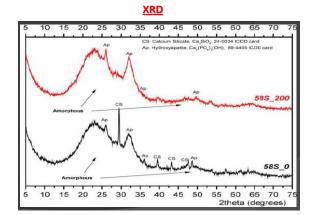
XRD

X-ray Powder Diffraction

More appropriately called polycrystalline X-ray diffraction, because it can also be used for sintered samples, metal foils, coatings and films, finished parts, etc.

Used to determine

- phase composition (commonly called phase ID)- what phases are present?
- quantitative phase analysis- how much of each phase is present?
- unit cell lattice parameters, crystal structure
- average crystallite size of nanocrystalline samples
- crystallite microstrain and texture
- residual stress (really residual strain)



<u>XRD</u>

Applications of X-Ray Diffraction

- Determination of Crystal structure
- Phase identification / transition
- Grain size / micro-strain
- Texture/stress(i.e.polymer, fiber)
- Determination of thin film composition
- Industry Identification of archeological materials

XRD

Advantages of XRD

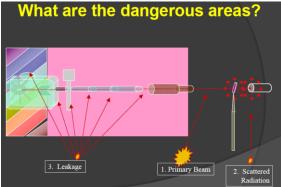
- Fast identification of materials,
- Easy sample preparation,
- Computer-aided material identification,
- Large library of known crystalline structures.

XRD

Safety in XRD

- Exposure types
 - Short-term high-dose
 - Long-term low-dose
- Invisible, odorless, colorless (most exposures undetectable)
- Lab users must understand radiation safety issues and pass an exam to use lab
- Safeguards present in lab do not substitute for knowledge and following safe procedures

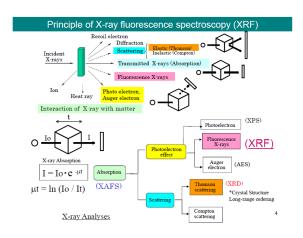
<u>XRD</u>



XRD

Summary & Conclusion

- X-ray diffraction is a technique for analyzing structures of biological molecules
- X-ray beam hits a crystal, scattering the beam in a manner characterized by the atomic structure
- Even complex structures can be analyzed by x-ray diffraction, such as DNA and proteins
- This will provide useful in the future for combining knowledge from physics, chemistry, and biology



XRF

Principle of X-ray fluorescence spectroscopy (XRF) 2 photoelectron emission Replace Spectroscopy (XRF) 3 Fluorescence X-ray(Ka) Core electron 1)X-ray irradiation with energy E Bohr model and emission of X-ray fluorescence

X-ray energy E > Binding energy Eb

XRF

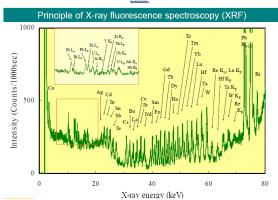
Principle of X-ray fluorescence spectroscopy (XRF) Incident X-rays Fluorescence X-rays Fluorescence X-rays Fluorescence Electron ΔE Fluorescence ΔE Fluoresce

 ΔE is equal to the energy difference between the two electronic state



ex) Flame reaction The color (energy) is unique to element

XRF



XRF

Principle of X-ray fluorescence spectroscopy (XRF)

Energy ∆E

→ characteristic to each element

Qualitative analysis

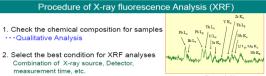
Chemical Composition Analyses

XRF

How to measure E and I of the fluorescence X-rays.

(a) Wavelength dispersive spectroscopy d-spacing Analyzing crystal WDS Bragg condition $n\lambda = 2d\sin\theta$ Energy of fluorescent X-ray can be selected by controlling Bragg angle Detector Electronics Computer High Efficiency (b) Energy dispersive spectroscopy Multi-elemental detection Detector Electronics Computer The detector should detect both Energy and Intensity of fluorescent X-ray EDS → SSD, SDD

XRF



- Combination of X-ray source, Detector, measurement time, etc. 3. Make calibration curve from standards
- 4. Calculate elemental concentration for the sample from the peak intensity
 ... Quantitative Analysis

Energy / eV Concentration (ppm) Calibration Curve for Cd R₂=0.9996, LLD=3.5 (ppm)

XRF

Probes used



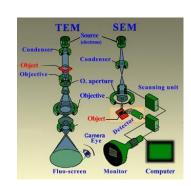
- Visible light
- Optical microscopy (OM)
- X-ray
- X-ray diffraction (XD)
- X-ray photo electron spectroscopy (XPS)
- Neutron
- Neutron diffraction (ND) lon
- Secondary ion mass spectrometry (SIMS)
- Cleaning and thinning samples
- Electron
- Scanning electron microscopy (SEM)
- Transmission electron microscopy (TEM)
- Electron holography (EH)
- Electron diffraction (ED)
- Electron energy loss spectroscopy (EELS)
- Energy dispersive x-ray spectroscopy (EDS) Auger electron spectroscopy (AES)

Electron Microscopy

Introduction and History

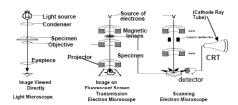
- o Electron microscopes are scientific instruments that use a beam of energetic electrons to examine objects on a very
- $_{\rm O}$ Electron microscopes were developed due to the limitations of Light Microscopes which are limited by the physics of light.
- o In the early 1930's this theoretical limit had been reached and there was a scientific desire to see the fine details of the interior structures of organic cells (nucleus, mitochondria...etc.).
- $\scriptstyle\rm O$ This required 10,000x plus magnification which was not possible using current optical microscopes.

SEM - TEM



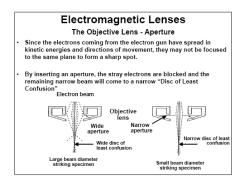
SEM - TEM

Comparison of OM, TEM and SEM

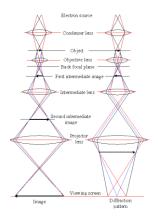


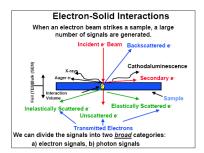
Principal features of an optical microscope, a transmission electron microscope and a scanning electron microscope, drawn to emphasize the similarities of overall design.

SEM - TEM



SEM - TEM





SEM - scanning electron microscopy

$\lambda = h/(2m_{\rm electron}qV_{\rm o} + q^2Vo^2/c^2))^{1/2}$

Effects of increasing voltage in electron gun:

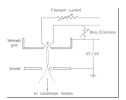
Resolution increased (A decreased)

Penetration increases

Specimen charging increases (insulators)

Specimen damage increases

Image contrast decreases



SEM - scanning electron microscopy

Scanning electron microscopy is used for inspecting topographies of specimens at very high magnifications using a piece of equipment called the scanning electron microscope. SEM magnifications can go to more than 300,000 X but most semiconductor manufacturing applications require magnifications of less than 3,000 X only. SEM inspection is often used in the analysis of die/package cracks and fracture surfaces, bond failures, and physical defects on the die or package surface.

During SEM inspection, a beam of electrons is focused on a spot volume of the specimen, resulting in the transfer of energy to the spot. These bombarding electrons, also referred to as primary electrons, dislodge electrons from the specimen itself. The dislodged electrons, also known as secondary electrons, are attracted and collected by a positively biased grid or detector, and then translated into a signal.

To produce the SEM image, the electron beam is swept across the area being inspected, producing many such signals. These signals are then amplified, analyzed, and translated into images of the topography being inspected. Finally, the image is shown on a CRT.

SEM - scanning electron microscopy

- The energy of the primary electrons determines the quantity of secondary electrons collected during inspection. The emission of secondary electrons from the specimen increases as the energy of the primary electron beam increases, until a certain limit is reached. Beyond this limit, the collected secondary electrons diminish as the energy of the primary beam is increased, because the primary beam is already activating electrons deep below the surface of the specimen. Electrons coming from such depths usually recombine before reaching the surface for emission.
- Aside from secondary electrons, the primary electron beam results in the emission of backscattered (or reflected) electrons from the specimen. Backscattered electrons possess more energy than secondary electrons, and have a definite direction. As such, they can not be collected by a secondary electron detector, unless the detector is directly in their path of travel. All emissions above 50 eV are considered to be backscattered electrons.

SEM - scanning electron microscopy

- Backscattered electron imaging is useful in distinguishing one material from another, since the yield of the collected backscattered electrons increases monotonically with the specimen's atomic number. Backscatter imaging can distinguish elements with atomic number differences of at least 3, i.e., materials with atomic number differences of at least 3 would appear with good contrast on the image. For example, inspecting the remaining Au on an Al bond pad after its Au ball bond has lifted off would be easier usin backscatter imaging, since the Au islets would stand out from the Al background.
- A SEM may be equipped with an EDX analysis system to enable it to perform compositional analysis on specimens. EDX analysis is useful in identifying materials and contaminants, as well as estimating their relative concentrations on the surface of the specimen.

SEM - scanning electron microscopy

1.1 Characteristic Information: SEM

The surface features of an object or "how it looks", its texture; direct relation between these features and materials properties

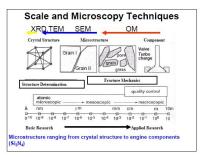
Morphology
The shape and size of the particles making up the object; direct relation between these structures and materials properties

The elements and compounds that the object is composed of and the relative amounts of them; direct relationship between composition and materials properties

Crystallographic Information

How the atoms are arranged in the object; direct relation between these arrangements and material properties

SEM - scanning electron microscopy



SEM - scanning electron microscopy

Advantages of Using SEM over OM

~ 0.2mm

1.5nm

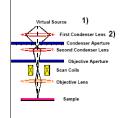
Depth of Field OM: 4x - 1400x SEM: 10x - 500Kx 30mm

The SEM has a large depth of field, which allows a large amount of the sample to be in focus at one time and produces an image that is a good representation of the three-dimensional sample.

The combination of higher magnification, larger depth of field, greater resolution, compositional and crystallographic information makes the SEM one of the most heavily used instruments in academic/national lab research areas and industry.

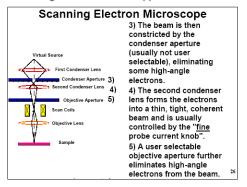
SEM - scanning electron microscopy

Scanning Electron Microscope

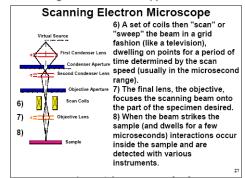


- 1) The "Virtual Source" at the top represents the electron gun, producing a stream of monochromatic electrons.
- 2) The stream is condensed by the first condenser lens (usually controlled by the coarse probe current knob"). This lens is used to both form the beam and limit the amount of current in the beam. It works in conjunction with the condenser aperture to eliminate the high-angle electrons from the beam.

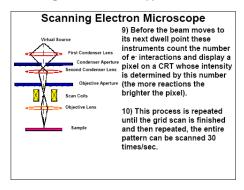
SEM - scanning electron microscopy



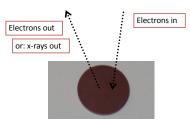
SEM - scanning electron microscopy



SEM - scanning electron microscopy



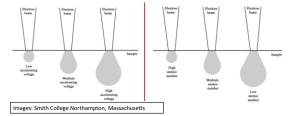
How do we get an image?



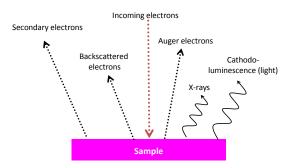
• In brief: we shoot high-energy electrons and analyze the outcoming electrons/x-rays

Electron beam-sample interactions

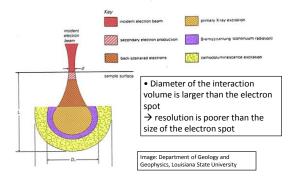
- The incident electron beam is scattered in the sample, both elastically and inelastically
- This gives rise to various signals that we can detect (more on that on next slide)
- Interaction volume increases with increasing acceleration voltage and decreases with increasing atomic number



Signals from the sample



Where does the signals come from?



Secondary electrons (SE)

- Generated from the collision between the incoming electrons and the loosely bonded outer electrons
- Low energy electrons (~10-50 eV)
- Only SE generated close to surface escape (topographic information is obtained)
- Number of SE is greater than the number of incoming electrons
- We differentiate between SE1 and
 SE2





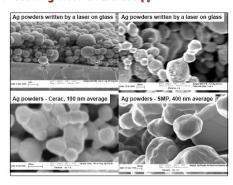
Why do we need vacuum?

- Chemical (corrosion!!) and thermal stability is necessary for a well-functioning filament (gun pressure)
 - A field emission gun requires $^{\sim}$ 10⁻¹⁰ Torr
 - LaB_6 : $\sim 10^{-6} Torr$
- The signal electrons must travel from the sample to the detector (chamber pressure)
 - Vacuum requirements is dependant of the type of detector

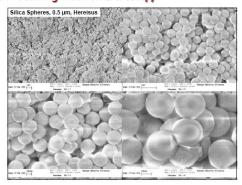
SEM - scanning electron microscopy



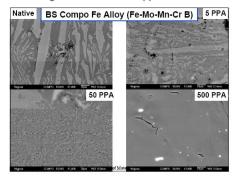
SEM - scanning electron microscopy



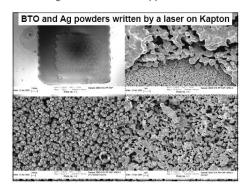
SEM - scanning electron microscopy



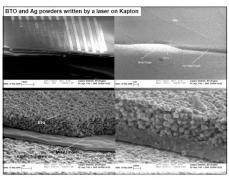
SEM - scanning electron microscopy



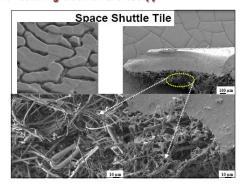
SEM - scanning electron microscopy



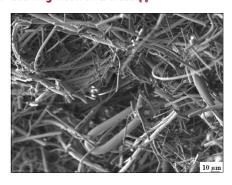
SEM - scanning electron microscopy



SEM - scanning electron microscopy



SEM - scanning electron microscopy



SEM - scanning electron microscopy

